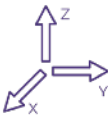


S, SH & SD Series

Compact Design, Capacitive Sensor Close-loop Control

Multi Degrees of Freedom, Travel Range up to 500 μm , High Dynamic and High Load optional

Standard

1 Axis		S100.X.C 100 μm	S300.X.C 300 μm	S500.X.C 500 μm
		S100.Z.C 100 μm	S300.Z.C 300 μm	
2 Axes		S100.XY.C 100 μm , 100 μm	S300.XY.C 300 μm , 300 μm	S500.XY.C 500 μm , 500 μm
3 Axes		S100.XYZ.C 100 μm , 100 μm , 100 μm	S200.XYZ.C 200 μm , 200 μm , 200 μm	

* Non-magnetic, Ultra High Vacuum Versions available

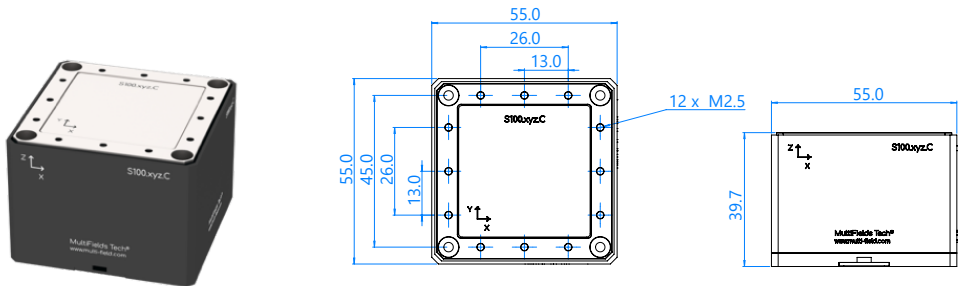


XY/XYZ Piezo Scanner — S100.XY/XYZ, S200.XY/XYZ

Compact XYZ Stack System

- Feature
- Piezo Stack Driving
 - Direct Metrology
 - Flexure Guiding
 - Sub-nanometer Resolution
 - CAP Sensor, Close-loop Control
 - Compact Serial Structure

➤ Photo & Drawing



➤ Specification

S100.XY.C

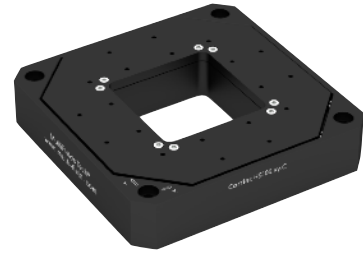
S200.XY.C

S100.XYZ.C

S200.XYZ.C

1	Optional	.NM, Non-magnetic; .HV, High Vacuum Version; .UHV, Ultra High Vacuum Version;			
2	Motion Direction	X, Y		X, Y, Z	
3	Footprint × Height	55 × 55 × 27 mm	55 × 55 × 30 mm	55 × 55 × 40 mm	55 × 55 × 45 mm
4	Material	Aluminum, Stainless Steel			
5	Travel Range (Open-loop)	120 × 120 μm	240 × 240 μm	120 × 120 × 120 μm	240 × 240 × 240 μm
6	Travel Range (Close-loop)	100 × 100 μm	200 × 200 μm	100 × 100 × 100 μm	200 × 200 × 200 μm
7	Resolution (Open-loop)	0.2 nm	0.4 nm	0.2 nm	0.4 nm
8	Resolution (Close-loop)	1 nm	1.5 nm	1 nm	1.5 nm
9	Linearity	0.03%			
10	Resonant Frequency (X/Y/Z no load)	400 / 350 / – Hz	300 / 250 / – Hz	400 / 350 / 300 Hz	300 / 250 / 200 Hz
11	Stiffness	0.5 N/μm	0.25 N/μm	0.5 N/μm	0.25 N/μm
12	Sensor Type	Capacitive			
13	Driving Voltage	Max. 150 V			
14	Working Temperature	15 ~ 40 °C			
15	Cable	D-Sub 3W3			
16	Controller	MC-Archimedes.N			

* For detail drawing and 3D model please contact us.



Travel Range – 200 μm

Travel Range – 300 μm

[Carrier.S200.Z.C](#)

200 μm

[Carrier.S200.XY.C](#)

200 μm , 200 μm

[Carrier.S200.XYZ.C](#)

200 μm , 200 μm , 200 μm

[Carrier.S300.XYZ.C](#)

300 μm , 300 μm , 300 μm

[Carrier.S200.XYRz.C](#)

200 μm , 200 μm , ± 2 mrad

[Carrier.S200.ZTxTy.C](#)

200 μm , ± 2 mrad, ± 2 mrad

[Carrier.S200.XYZTxTyRz.C](#)

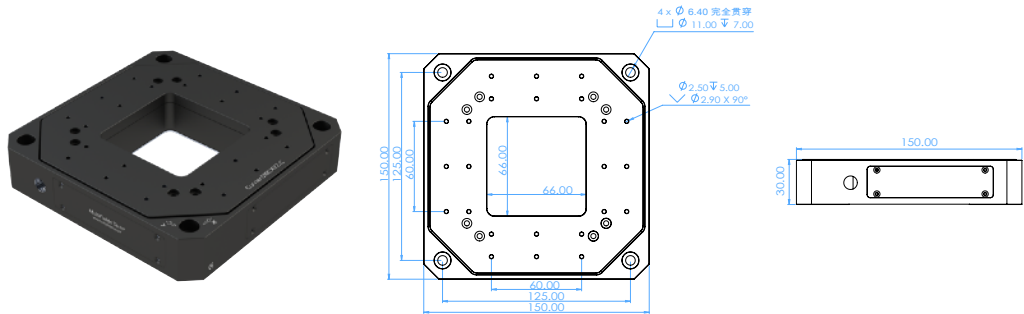
200 μm , 200 μm , 200 μm , ± 2 mrad,
 ± 2 mrad, ± 2 mrad

XYZ Piezo Scanner — Carrier.S100/200/300.XYZ.C

Versatile, High Performance, Clear Aperture, XYZ Motion

- ➔ Feature
- Piezo Stack Driving
 - Direct Metrology
 - Flexure Guiding
 - Sub-nanometer Resolution
 - CAP Sensor, Close-loop Control
 - Large Aperture

➔ Photo & Drawing



➔ Specification

		Carrier.S100.XYZ.C	Carrier.S200.XYZ.C	Carrier.S300.XYZ.C
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1	Optional	.NM, Non-magnetic; .HV, High Vacuum Version; .UHV, Ultra High Vacuum Version;		
2	Motion Direction	XYZ		
3	Footprint × Height	150 × 150 × 30 mm		
4	Material	Aluminum, Stainless Steel		
5	Travel Range(XYZ)	100 x 100 x 100 μm	200 x 200 x 200 μm	300 x 300 x 300 μm
6	Aperture	66 × 66 mm		
7	Resolution (Close-loop/Open-loop)	1 nm / 0.3 nm	1.5 nm / 0.4 nm	2 nm / 0.5 nm
8	Repeatability	10 nm	10 nm	10 nm
9	Linearity(XYZ)	0.03%		
10	Crosstalk (Z-XY)	±30 nm	±50 nm	
11	Resonant Frequency (XYZ no load)	180 / 180 / 390 Hz	155 / 155 / 320 Hz	135 / 135 / 250 Hz
12	Resonant Frequency (XYZ 350 g)	150 / 150 / 250 Hz	120 / 120 / 200 Hz	90 / 90 / 140 Hz
13	Max. Payload	5 kg		3 kg
14	Sensor Type	Capacitive		
15	Driving Voltage	Max. 150 V		
16	Working Temperature	15 ~ 40 °C		
17	Controller	MC-Archimedes.N		

* For detail drawing and 3D model please contact us.